

GROUP 1700

MAY 30 2003

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Docket No. AM1562D1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

YIQIONG WANG

Confirmation No. 8856

Serial No.: 09/882,141

Examiner: Umez-Eronini

Filed: June 15, 2001

Group Art Unit: 1765

For: METHOD OF ETCHING HIGH ASPECT
RATIO OPENINGS IN SILICON

RESPONSE UNDER 37 CFR 1.115

To: Assistant Commissioner for Patents
Washington, DC 20231

Sir:

In response to the office action of February 25, 2003,
please amend the above-identified application as follows.